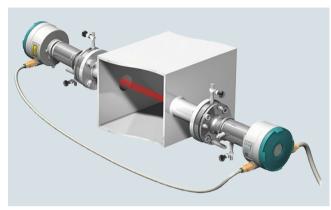
In situ O2 gas analyzer

### Overview



#### SITRANS SL

SITRANS SL is a diode laser gas analyzer with a measuring principle based on the specific light absorption of different gas components. SITRANS SL is suitable for fast, non-contact measurement of gas concentrations in process or flue gases. An analyzer consisting of transmitter and receiver units (sensors) is used for each measuring point. The hardware for further processing of the measured signal into a concentration value, as well as the monitoring, control and communication functions, are integrated in these two main modules. The sensors are designed for operation under harsh environmental conditions.

#### Benefits

The in-situ SITRANS SL gas analyzer features high operational availability, unique analytical selectivity, and a wide range of possible applications. SITRANS SL permits measurement of a gas component directly in the process:

- With high dust load
- In hot, humid, corrosive, explosive, or toxic gases
- In applications showing strong varying gas compositions
- Under harsh environmental conditions at the measuring point
- Highly selective, i.e. mostly without cross-sensitivities

Special features of the SITRANS SL:

- · Little installation effort
- Minimum maintenance requirements
- Extremely rugged design
- High long-term stability through built-in, maintenance-free reference gas cell
- Real-time measurements

Moreover, the analyzer provides warning and error messages:

- When maintenance is required
- With large variations in the reference signal
- With poor signal quality
- If the transmission violates an upper or lower limit

### Application

#### Applications

- Control of combustion processes
- Process optimization
- Plant and operator safety
- Process measurements in all types of power and combustion plants
- Process control
- Explosion protection
- · Measurements in corrosive and toxic gases
- · Quality control

#### Sectors

- · Chemical and petrochemical plants
- Power plants
- Waste incinerators
- Iron and steel industry

#### In situ O2 gas analyzer

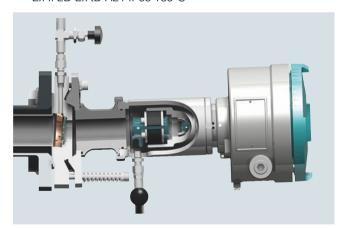
#### Design

The SITRANS SL gas analyzer consists of a pair of cross-duct sensors, a transmitter unit and a detector unit, both with the same dimensions. The complete analyzer is integrated in these two enclosures. The transmitter unit contains the laser source whose light is transmitted to the receiver through the measurement path. The detector unit contains a photodetector including electronics as well as a reference cell. The detector unit is connected to the transmitter unit by means of a sensor cable. A further cable on the receiver is used to connect the power supply and the communication interfaces. The receiver enclosure contains a local user interface (LUI) with an LC display which can be read through a window in the cover. The LUI is operated by remote-control.

#### Transmitter and detector units

Special features of the transmitter and detector units:

- In-situ cross-duct sensors, designed as transmitter and detector units, connected via sensor cable
- · Powder-coated aluminium; stainless steel
- Degree of protection IP65
- Adjustable process connection plates
- Flange sizes (provided by customer): DN50/PN25, ANSI 4"/ 150 lbs
- Purging gas connections (see "Purging")
- Optional: Explosion-protected version in accordance with - Ex II 2G Ex de op is IIC T6 Ex II 2D Ex tD A21 IP65 T85°C



SITRANS SL, detector unit

#### Parts in contact with the process gas

Only the stainless steel flange of the sensor with borosilicate window and FFKM seal comes in contact with the process gas. This has optional connections for purging the process gas side with an appropriate gaseous medium.

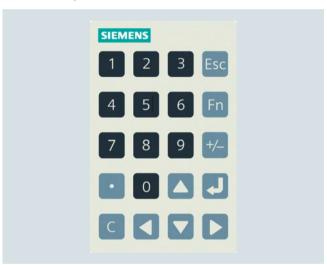
#### Display and control panel

Special features of the detector unit:

- Display for simultaneous output of result and device status
- · LED backlighting of display
- Remote control with infrared interface for simplified configuration and operation for safe implementation in hazardous areas
- Menu-driven operation for parameterization and diagnostics



Local user interface (LUI) of SITRANS SL in the detector unit (display of measured value)



Remote control keypad for SITRANS SL

#### Connection cables

SITRANS SL is supplied as standard without connecting cables. These must be provided by the customer or are available as accessories. Exception: The standard ATEX version is supplied with pre-installed cabling.

The sensor cable connects together the transmitter and detector units of the analyzer.

The sensor connecting cable available as a cable set for the ATEX version as standard, and for non-Ex applications optionally, is offered in lengths of 5, 10 or 25 m. This (optional) cable set also enables permanent installation of an Ethernet cable used for service and maintenance purposes.

A rugged cable sleeve should be used as UV protection for installations in open cable ducts or channel systems.

The statutory directives must be observed in the event of installation in hazardous areas.

For the ATEX version of SITRANS SL, the sensor connecting cable must be connected between the two Ex-e terminal boxes secured on the transmitter and receiver units.

## In situ continuous process gas analysis

SITRANS SL

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#### Inputs/outputs

- 2 analog inputs (4 to 20 mA) for process gas temperature and pressure
- 2 analog outputs (4 to 20 mA) for gas concentration or for concentration and transmission
- 1 configurable digital input
  - 2 configurable digital outputs (display of faults, maintenance requirement, function monitoring, alarms for limit violations of measured value or transmission)
- 1 Ethernet 10Base-TX port, only for servicing and maintenance

#### Optional

- 1 Modbus interface with
  - Output of concentration as cyclic data
- Alarm output, alarm classification
- Input for temperature and/or pressure data for compensation
- 1 PROFIBUS DP interface with:
  - Output of concentration as cyclic data
  - Alarm output, alarm classification
  - Input for temperature and/or pressure data for compensation

The PROFIBUS DP protocol provides DPV0, cyclic data. Measured values are provided with additional quality data.

#### Note:

In contrast to the other interfaces, the Ethernet plug-in connector on standard non-Ex devices is only accessible following removal of the detector unit cover. With the help of the sensor cable set (optional with non-Ex devices), an Ethernet cable can be permanently installed via the terminal box of the sensor connecting cable. The Ethernet connection via the sensor cable can also only be used for temporary service and maintenance purposes.

#### NOTICE:

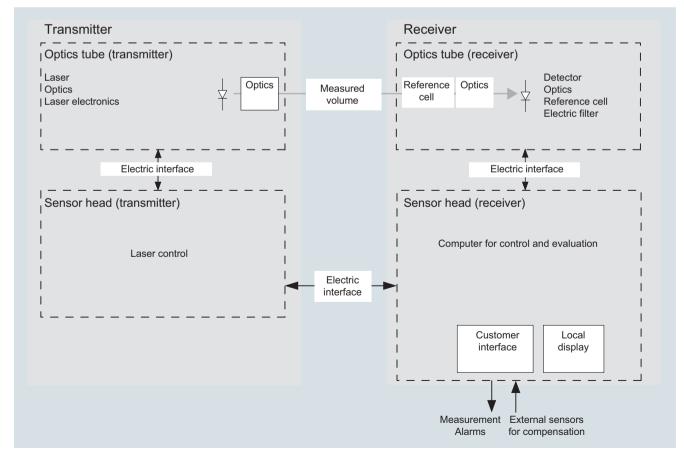
In an Ex environment, Ethernet connections may only be made or removed with the permission of the plant operator!

#### Function

#### Operating principle

SITRANS SL is a gas analyzer employing single-line molecular absorption spectroscopy. A diode laser emits a beam of infrared light which passes through the process gas and is received by a detector unit. The wavelength of the laser diode output is tuned

to a gas-specific absorption line. The laser continuously scans this single absorption line with a very high spectral resolution. The degree of absorption and the line shape are used for the evaluation.

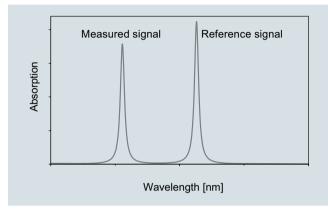


Basic design of the SITRANS SL

#### In situ O2 gas analyzer

The field design of the SITRANS SL in-situ gas analyzer consists of a transmitter unit and a detector unit. The light which is not absorbed by the sample is detected in the receiver. The concentration of the gas component is determined from the absorption.

The SITRANS SL analyzer measures a single gas component by means of the absorption capacity of a single fully resolved molecular absorption line.



Absorption spectrum of measured signal and reference signal with SITRANS SL

SITRANS SL is designed for measuring oxygen (O<sub>2</sub>) with high sensitivity.

Typical application specifications:

Oxygen concentration 0 ... 100 vol % Process pressure/temperature conditions (with  $O_2$  application) 700 ... 5 000 hPa (absolute)/ 0 ... 200 °C 900 ... 1 100 hPa (absolute)/ 0 ... 600 °C

The measuring performance of the SITRANS SL depends, among others, on the actual, individual process conditions with regard to concentration ranges, pressure and temperature.

An internal reference cell is used to constantly check the stability of the spectrometer.

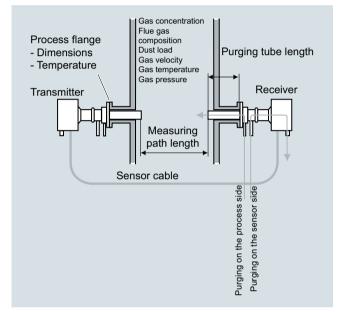
The self-calibration of the analyzer is therefore valid for one year without the need for external recalibration using calibration gases.

#### Configuration

A feature of the in-situ analytical procedure is that the physical measurement takes place directly in the stream of process gas and directly in the actual process gas line. All process parameters such as gas matrix, pressure, temperature, moisture, dust load, flow velocity and mounting orientation can influence the measuring properties of the SITRANS SL and must therefore be investigated for each new application.

The standard applications listed in the ordering data for the SITRANS SL are distinguished in that the typical process conditions are adequately well-known and documented. If you cannot find your application among the standard applications, please contact Siemens. We will be pleased to check your possible individual application of the SITRANS SL. You can find an application questionnaire on the website for the SITRANS SL:

http://www.siemens.com/insituquestionnaire



Typical cross-duct arrangement of the SITRANS SL

The SITRANS SL can be optionally purged on the process side using appropriate purging gases to prevent contamination of the sensor optics on the process side. Purging tubes on the sensor heads, which slightly extend into the process gas stream, define the effective measuring path length.

In situ O2 gas analyzer

#### Influences on the measurement

#### Dust load

As long as the laser beam is able to generate a suitable detector signal, the dust load in the process gas does not influence the analytical result. By applying a dynamic background correction, measurements can be carried out without any negative impact. Under optimal conditions, the SITRANS SL can cope with dust loads up to 20 g/Nm³ and up to a measured path length of 8 m. The influence of a high dust load is extremely complex, and depends on the optical path length and particle size. The optical attenuation increases exponentially at longer path lengths. Smaller particles also have a very large influence on the optical attenuation. With high dust load, long path length and small particle size, the technical support at Siemens should be consulted.

#### Temperature

The influence of temperature on the absorption line is compensated by a correction file. A temperature signal can be fed into the instrument from an external temperature sensor. The signal is then used for mathematical correction of the influence of the temperature on the concentration strength. If the process gas temperature remains constant, a static correction can be carried out as an alternative. Without temperature compensation, the relative error caused by changes in the gas temperature has an extensive effect on the measurement (e.g. up to 0.24 %/K with the  $\rm O_2$  application). An external temperature signal is therefore recommended in most cases.

#### Pressure

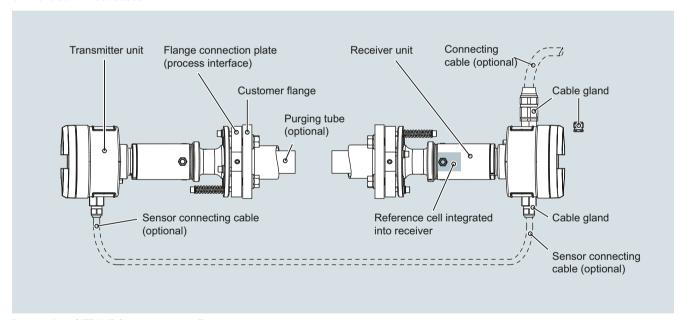
In addition to the temperature signal, an external pressure signal can be fed to the instrument to provide complete mathematical compensation for the pressure influence including the density effect. Without compensation, the relative error caused by changes in the process gas pressure is approx. 0.1 %/hPa. An external pressure signal is therefore recommended in most cases

#### Effective optical path length

As a result of Beer-Lambert's law, the absorption of laser light depends on the optical path length within the sample gas. Therefore the precision of the effective optical path length measurement can have an effect on the precision of the total measurement.

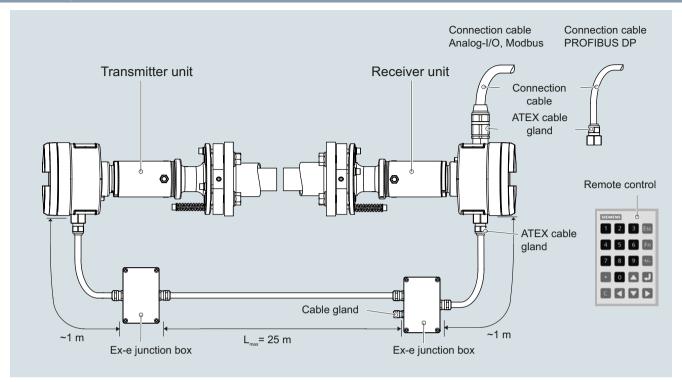
Since the sensor optics on the process side usually has to be purged to keep it clean for a longer period, the extent of the mixed zone between the purging medium and the process gas as well as the latter's concentration distribution must be considered. In a typical in-situ installation with an optical path length of several meters, the influence of the purging gas on the effective path length can be ignored.

The maximum possible path length and dust load mutually affect each other: the higher the dust load in the process, the shorter the max. possible path length.

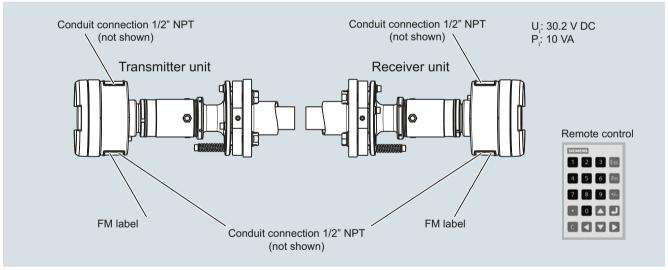


Design of the SITRANS SL system in non-Ex version

### In situ O2 gas analyzer



Design of the SITRANS SL system in ATEX version



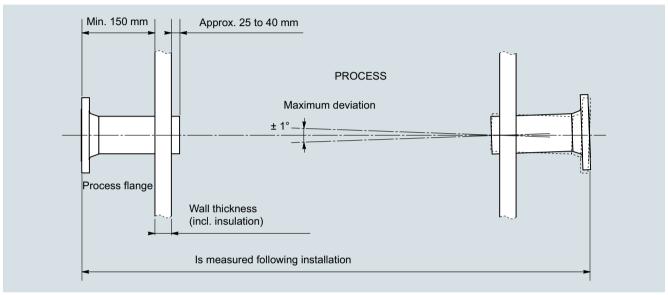
Design of the SITRANS SL system in FM version

The transmitter and detector units are mounted on process flanges provided by the customer. Correct alignment of these flanges must be guaranteed, e.g. by using the optional sensor alignment kit.

In situ O2 gas analyzer

#### Adjustment of the pair of sensors

The flange connection plates (process interface) of the SITRANS SL to the process flanges on the customer side must be correctly aligned so that the laser beam generated by the transmitter hits the photodetector in the detector unit This is guaranteed in that the transmitter and detector units have a curved surface integrated in the connection plates. The adjustment is carried out by shifting the flanges on these surfaces, through which the symmetry axis is aligned. The axis can be offset by  $\pm 1$  degree, which means that the process flanges must be welded onto the process wall with at least this accuracy - see following figure.



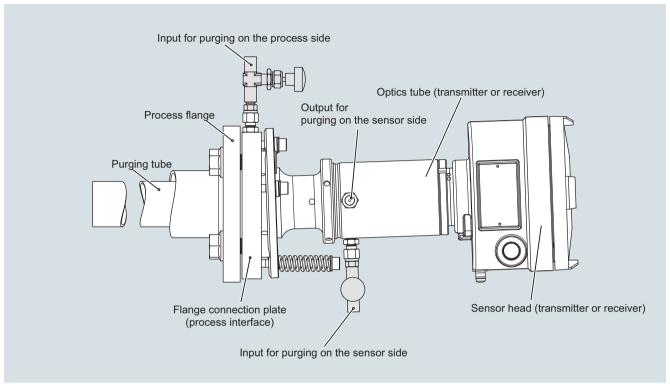
Installation/adjustment requirements for the pair of cross-duct sensors

#### In situ O2 gas analyzer

#### Purging

The easiest way to avoid condensation and dust deposits on the sensor windows or excessively high thermal load of the windows and the sealing material as well as the sensor electronics is to purge them (with  $O_2$  application: nitrogen). Purging must be selected depending on the application. The transmitted-light sensors can therefore be configured for the respective situation. The application reference table provides recommendations for suitable purging for the standard applications.

If oxygen is to be measured with the SITRANS SL - which is also present in measurable quantities in the ambient air - oxygen-free purging gases must be used, such as nitrogen. It is equally necessary to purge the inside of the sensor heads, since the ambient air must also be displaced here out of the laser beam path. A differentiation is therefore made between purging on the process side and purging on the sensor side.



Arrangement for purging on the sensor side of the SITRANS SL

#### Purging on process side

For purging on the process side, the flow of purging gas can be adjusted between 0 and approx. 50 l/min at each sensor head using a needle valve (included in delivery).

#### Purging on sensor side

This can be combined with the purging on the process side, if required. Purging with nitrogen on the sensor side is almost always necessary for  $\rm O_2$  applications to avoid an offset caused by the oxygen of the air present in the unit. The cells in the sensor head are then continuously purged with nitrogen. Particularly when (re)starting the SITRANS SL  $\rm O_2$ , a sufficiently high flow of purging gas of approx. 3 to 5 l/min must be provided for several minutes to ensure that all residues of oxygen are removed. The flow of sensor purging gas can subsequently be set to a lower value using the needle valve (included in delivery).

#### Note

With purging on the process side, it may be necessary to use non-return valves to ensure no process gas can enter the purging gas line in the event of failure of the purging gas supply. This applies especially in the case of cascaded process and sensor purging where there is otherwise the danger that, for example, corrosive process gases could enter the sensor enclosure.

## In situ continuous process gas analysis

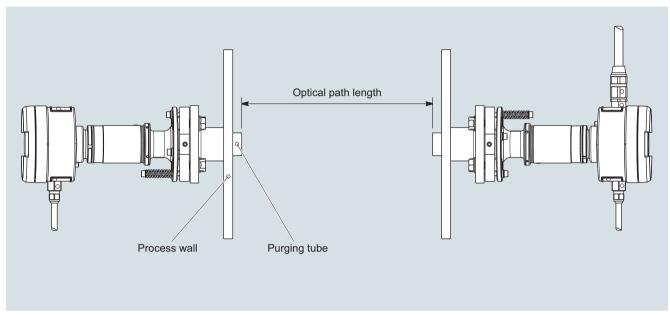
SITRANS SL

In situ O2 gas analyzer

#### Purging tubes

The purging media used on the process side flow through purging tubes into the process gas stream. The tubes extend into the process area by a few centimeters, usually perpendicular to the process gas stream. This means that an exactly defined optical path length is defined through the sample gas. The effective

measuring path in the process gas is therefore defined as the distance between the ends of the two purging tubes. The standard length of the purging tubes is 340 mm. To achieve sufficient calibration of the transmitter and receiver, the process wall should be max. 150 mm thick.



Measurement of the optical path length between the ends of the purging gas tubes

#### Maintenance and fault messages

The SITRANS SL carries out continuous self-monitoring, and outputs alarms and warnings to indicate maintenance requirements or a system fault. The information is output as plain text on the LUI display, where symbols identify the category and the severity of the fault.

#### Alarm categories:

- Maintenance (system must be cleaned or repaired)
- Process value (problem with external sensor, or process conditions outside the permissible range for SITRANS SL)
- Configuration (SITRANS SL is not correctly configured)

#### Severity:

- Fault (measurements could not be carried out)
- Warning (measurements may be inaccurate, or the system will soon shut down measuring mode if an intervention is not made)
- Advanced warning/information (measurements are carried out)

The two binary (relay) outputs can be configured freely for the alarm output.

The response of the analog outputs in the event of an alarm is configurable; possible actions are:

- Off (current measured value is displayed)
- Last measured value (freezing of last value displayed)
- Standard level (setting to predefined value)
- 3 mA (NAMUR NE43 fault status)

In addition, the transmission is available as an output variable.

#### Note

Specific requirements for the measuring point can make the utilization of special sensor equipment necessary. The possibilities for adapting the sensors are:

- Special materials for purging tubes (on request)
- Various types/sizes of sensor flanges
- Explosion-protected sensor configurations

#### Essential characteristics

- Long-term stabilization by using an internal reference cell; for calibration interval of at least one year
- Dynamic background correction for varying dust loads
- Isolated signal outputs of 4 to 20 mA
- User-friendly, menu-driven operation
- Selectable time constants (response time)
- Password-protected user interface
- I/O operation in accordance with NAMUR recommendations
- · Monitoring of overall optical transmission
- Sensor enclosure resistant to wear and corrosion
- Simple local operation using remote-control unit with numeric keypad and menu prompting

## In situ continuous process gas analysis

SITRANS SL

#### In situ O2 gas analyzer

#### Standard applications

The following table lists the measuring conditions for standard applications. The listed values for the measuring range and detection limit are only approximate values. The exact values at the respective measuring point depend on the totality of all influencing variables and can be determined by Siemens for the specific

case. Note that the values for the detection limit and the maximum measuring range are based on a path length of 1 m. Longer path lengths will improve the detection limit, but not linearly. This is due to limiting effects such as dust load. The maximum applicable measuring ranges can only be used if permitted by the process conditions such as dust load.

Standard application Effective optical path length: 0.3 8 m Dust load <sup>2)</sup> : < 50 g/Nm <sup>3</sup>		Process gas temperature T <sub>min</sub> T <sub>max</sub>	pressure p <sub>min</sub> p <sub>max</sub>	Min. mea- suring range (with 1 m eff. opt. path length)	range (also dependent on	suring range x path length	DL x path length (under standard conditions <sup>1)</sup> without cross- interference of other gases)	ability <sup>3)</sup>	Purging gas medium	
Sample gas component	Gas code	Appl. code								
O <sub>2</sub>	А	В	0 600 °C	900 1 100 hPa	0 1 vol%	0 100 vol%	75 vol%*m	200 ppmv*m	2%	N <sub>2</sub>
O <sub>2</sub>	А	С	0 200 °C	700 5 000 hPa	0 1 vol%	0 100 vol%	75 vol%*m	200 ppmv*m	2%	N <sub>2</sub>

Reference table: Standard applications. The specified pressures are absolute.

DL = detection limit

The specification applies at 20 °C and 1013 hPa in a nitrogen atmosphere. In rare cases, a deviating process gas matrix or process conditions can have a negative effect on performance. Contact Siemens to determine the exact performance under your process conditions.

With 0.3 m effective optical path length

Average diameter of the dust particles: 15 µm
Specific weight of the dust particles: 650 kg/m<sup>3</sup>
The influence of dust load is extremely complex and depends on the path length and particle size. The optical attenuation increases exponentially at longer path lengths. Smaller particles also have a very large influence on the optical attenuation. With high dust load, long path length and small particle size, the technical support at Siemens should be consulted.

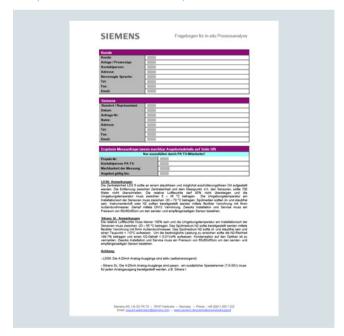
3) Based on measuring range. With stable or externally measured and software-compensated process gas temperature and pressure conditions

### Special applications

In addition to the standard applications, special applications are available upon request. If the process conditions deviate from the specifications of the standard applications, special applications are also possible on request.

Complete the application questionnaire which can be found on the Internet at

http://www.siemens.com/insituquestionnaire:



In situ O2 gas analyzer

## Technical specifications

Analytical performance       Electrical characteristics         Measuring range       Internally adjustable       Auxiliary power       24 V DC nominal (18 30. 4 Auxiliary power         Detection limit at standardized conditions:       25 °C gas temperature, 1 000 hPa, 1 m accordance with EN 613 integration time and constant ambient conditions.       In accordance with EN 613 in accordance with EN 614 in accordance with EN 615 in accordance with	
Detection limit at standardized conditions: 25 °C gas temperature, 1 000 hPa, 1 m effective optical path length, 3 s integration time and constant ambient conditions.  Linearity (under standard conditions)  Repeatability (under standard conditions)  Design  Transmitter and detector units, connected by a sensor cable  Materials  Power consumption, maximum  EMC  Electrical safety Fuse specifications  T1.6L250V  Dynamic performance  Warm-up time at 20 °C ambient temperature Response time (T90)  Approx. 2 s, depends on a  Integration time  O 100 s, selectable  Influencing variables  Variations in ambient temperature  Process gas temperature  Process gas temperature  Process gas temperature  Process gas pressure  Process gas pressure  Process gas pressure  Process gas pressure  Variations in supply voltage  Parts wetted by the process gases  Parts wetted by the process gases  Parts wetted by the process gases  Process gas temperature  Process gas pressure  Variations in supply voltage  Variations in supply voltage  Parts wetted by the process gases  Process gas pressure  Process gas pressure  Variations in supply voltage  Variations in supply voltage  Electrical inputs and outputs	
tions: 25 °C gas temperature, 1 000 hPa, 1 m effective optical path length, 3 s integration time and constant ambient conditions.  Linearity (under standard conditions)  Repeatability (under standard conditions)  General information  Design  Transmitter and detector units, connected by a sensor cable  Materials  Parts wetted by the process gases  Materials  EMC  Electrical safety Fuse specifications  T1.6L250V  Dynamic performance  Warm-up time at 20 °C ambient temperature  Warm-up time at 20 °C ambient temperature  Response time (T90) Approx. 2 s, depends on a lintegration time  In accordance with EN 610  Electrical safety Fuse specifications  T1.6L250V  Dynamic performance  Warm-up time at 20 °C ambient temperature  Response time (T90) Approx. 2 s, depends on a lintegration time  Influencing variables  Variations in ambient temperature  Vift compensation: < 1%/ the measuring range  Variations in atmospheric pressure  Process gas temperature  Variations in atmospheric pressure  Process gas pressure  Process gas pressure  Process gas pressure  Variations in supply voltage  Electrical inputs and outputs	2 V DC)
25 °C gas temperature, 1 000 hPa, 1 m effective optical path length, 3 s integration time and constant ambient conditions.  Linearity (under standard conditions)  Repeatability (under standard conditions)  Repeatability (under standard conditions)  Ceneral information  Design  Transmitter and detector units, connected by a sensor cable  Materials  Transmitter and detector units, connected by a sensor cable  Sensor enclosure: Treated aluminum/stainless steel (1.4305/303)  Process interface: Acid-resistant stainless steel (1.4404/316L)  Window: hardened borosilicate glass  Compressible gaskets: FKM, FF, EPDM (holder for reference cell)  Flat gaskets: Graphite  Parts wetted by the process gases  Parts wetted by the process gases  Medical path length, 3 s integration in accordance with EN 613  Electrical safety  Fuse specifications  T1.6L250V  Dynamic performance  Warm-up time at 20 °C ambient temperature  Response time (T90)  Approx. 2 s, depends on a lintegration time  0 100 s, selectable  Influencing variables  Variations in ambient temperature  Process gas temperature  Variations in atmospheric pressure  Variations in supply voltage  Negligible  Process gas pressure  Variations in supply voltage  Negligible  Variations in supply voltage  Variations in supply voltage  Variations in supply voltage  Negligible	
integration time and constant ambient conditions.  Linearity (under standard conditions)  Repeatability (under standard conditions)  Better than 1%  Ceneral information  Design  Transmitter and detector units, connected by a sensor cable  Materials  Sensor enclosure: Treated aluminum/stainless steel (1.4305/303)  Process interface: Acid-resistant stainless steel (1.440/4316L)  Window: hardened borosilicate glass  Compressible gaskets: FKM, FF, EPDM (holder for reference cell)  Fuse specifications  Total 1%  Dynamic performance  Warm-up time at 20 °C ambient temperature  Response time (T90)  Approx. 2 s, depends on a lintegration time  Influencing variables  Variations in ambient temperature  Variations in ambient temperature  Variations in atmospheric pressure  Process gas temperature  Variations in atmospheric pressure  Process gas pressure  Variations in supply voltage  Variations in supply voltage  Variations in supply voltage  Variations in supply voltage  Electrical inputs and outputs	26-1
Enter conditions.  Linearity (under standard conditions)  Repeatability (under standard conditions)  Repeatability (under standard conditions)  General information  Design  Transmitter and detector units, connected by a sensor cable  Materials  **Sensor enclosure: Treated aluminum/stainless steel (1.4305/303)  **Process interface: Acid-resistant stainless steel (1.4404/316L)  **Window: hardened borosilicate glass  Compressible gaskets: FKM, FF, EPDM (holder for reference cell)  **First wetted by the process gases**  Euse specifications  T1.6L250V  Dynamic performance  Warm-up time at 20 °C ambient temperature  Response time (T90)  Approx. 15 min  Approx. 15 min  Parts wetted aluminum/stainless steel (1.4305/303)  Integration time  O 100 s, selectable  Influencing variables  Variations in ambient temperature  Variations in ambient temperature  Variations in atmospheric pressure  Process gas pressure  O <sub>2</sub> : With compensation: < 4 000 hPa of the measuring variables  Variations in atmospheric pressure  Process gas pressure  Variations in supply voltage	10-1
Repeatability (under standard conditions)  General information  Design  Transmitter and detector units, connected by a sensor cable  Sensor enclosure: Treated aluminum/stainless steel (1.4305/303)  Process interface: Acid-resistant stainless steel (1.4404/316L)  Window: hardened borosilicate glass  Compressible gaskets: FKM, FF, EPDM (holder for reference cell)  Flat gaskets: Graphite  Parts wetted by the process gases  Parts wetted by the process gases  Warm-up time at 20 °C ambient temperature  Response time (T90)  Approx. 2 s, depends on a lintegration time  0 100 s, selectable  Influencing variables  Variations in ambient temperature  Process gas temperature  With compensation: < 1%/ the measuring range  Variations in atmospheric pressure  Process gas pressure  Variations in supply voltage  Process gas pressure  Variations in supply voltage	
Transmitter and detector units, connected by a sensor cable  Materials  Transmitter and detector units, connected by a sensor cable  Materials  Sensor enclosure: Treated aluminum/stainless steel (1.4305/303) Process interface: Acid-resistant stainless steel (1.4404/316L) Window: hardened borosilicate glass Compressible gaskets: FKM, FF, EPDM (holder for reference cell) Flat gaskets: Graphite  Parts wetted by the process gases  Parts wetted by the process gases  Perture  Response time (T90) Approx. 2 s, depends on a lintegration time Integration time  O 100 s, selectable  Influencing variables  Variations in ambient temperature  With compensation: < 1%/ the measuring range  Variations in atmospheric pressure Process gas pressure  O <sub>2</sub> : With compensation: < 4 000 hPa of the measuring Variations in supply voltage  Process gas pressure  Variations in supply voltage  Process gas pressure  Variations in supply voltage  Process gas pressure  Variations in supply voltage	
Design  Transmitter and detector units, connected by a sensor cable  • Sensor enclosure: Treated aluminum/stainless steel (1.4305/303) • Process interface: Acid-resistant stainless steel (1.4404/316L) • Window: hardened borosilicate glass • Compressible gaskets: FKM, FF, EPDM (holder for reference cell) • Flat gaskets: Graphite  Parts wetted by the process gases  Transmitter and detector units, connected by a sensor cable  Integration time  0 100 s, selectable  Variations in ambient temperature  With compensation: < 1%/the measuring range  Variations in atmospheric pressure  Variations in atmospheric pressure  Process gas pressure  Variations in supply voltage  Process gas pressure  Variations in supply voltage	
nected by a sensor cable  Materials  • Sensor enclosure: Treated aluminum/stainless steel (1.4305/303) • Process interface: Acid-resistant stainless steel (1.4404/316L) • Window: hardened borosilicate glass • Compressible gaskets: FKM, FF, EPDM (holder for reference cell) • Flat gaskets: Graphite  Parts wetted by the process gases  • Purging tubes, flanges, window ring, process purging: acid-resistant stainless steel  • Sensor enclosure: Treated aluminum/stainless  Variations in ambient temperature  Process gas temperature  Variations in atmospheric pressure	plication
Materials  • Sensor enclosure: Treated aluminum/stainless steel (1.4305/303) • Process interface: Acid-resistant stainless steel (1.4404/316L) • Window: hardened borosilicate glass • Compressible gaskets: FKM, FF, EPDM (holder for reference cell) • Flat gaskets: Graphite  Parts wetted by the process gases  • Purging tubes, flanges, window ring, process purging: acid-resistant stainless steel  • Sensor enclosure: Treated aluminum/stainless  Variations in ambient temperature  Process gas temperature  Variations in atmospheric pressure	
Parts wetted by the process gases  num/stainless steel (1.4305/303)  Process interface: Acid-resistant stainless steel (1.4404/316L)  Window: hardened borosilicate glass  Compressible gaskets: FKM, FF, EPDM (holder for reference cell)  Flat gaskets: Graphite  Parts wetted by the process gases  Process gas temperature  Variations in ambient temperature  Process gas temperature  Variations in ambient temperature  Variations in ambient temperature  Variations in ambient temperature  Variations in ambient temperature  Vith compensation: < 1%/ the measuring range  Negligible  Variations in ambient temperature	
stainless steel (1.4404/316L)  • Window: hardened borosilicate glass • Compressible gaskets: FKM, FF, EPDM (holder for reference cell) • Flat gaskets: Graphite  • Purging tubes, flanges, window ring, process purging: acid-resistant stainless steel  • Purging tubes and outputs  • Purging tubes and outputs  • Purging tubes, flanges, window ring, process purging: acid-resistant stainless steel	ng range
glass  • Compressible gaskets: FKM, FF, EPDM (holder for reference cell)  • Flat gaskets: Graphite  • Purging tubes, flanges, window ring, process purging: acid-resistant stainless steel  • Variations in atmospheric pressure  Process gas pressure  • Process gas pressure  • Variations in atmospheric pressure  • Process gas pressure  • Variations in supply voltage  • Process gas pressure  • Variations in atmospheric pressure  •	00 K of
Parts wetted by the process gases  Parts wetted by the process gases  Parts wetted by the process gases  Process gas pressure  Variations in supply voltage  Variations in supply voltage  Variations in supply voltage  Flectrical inputs and outputs  Electrical inputs and outputs	
ring, process purging: acid-resistant stainless steel  Figure process gases  Figure process purging: acid-resistant stainless steel	
tant stainless steel	
Window: Borosilicate Number of measurement channels 1	
<ul> <li>Gasket in window: FFKM</li> <li>Flat gasket between customer flange and process flange: Graphite</li> <li>Analog outputs</li> <li>2 outputs, 4 20 mA, float resistance max. 660 Ω. Ext lating power supplies may</li> </ul>	ernal iso-
Installation In-situ or bypass provided by the customer.	20. 4
Concentration units ppm, vol.%, mg/Nm $^3$ Analog inputs 2 inputs, designed for 4 120 $\Omega$	20 mA,
Display  Digital concentration display (4 digits with floating decimal point)  Digital outputs  Digital outputs  2 outputs, with switchover configurable, 24 V/0.5 A, fl configurable, 24 V/0.5 A, fl de pole double throw (SPI	ating, sin-
gio polo dodalo mon (o. 2	•
ATEX II 2G Ex de op is IIC T6     ATEX II 2D Ex tD A21 IP65 T85 °C     Configurable	loating,
• FM Class I, II, III Div 1 Groups A, B, Service port Ethernet 10BaseT (RJ-45) C, D, E, F, G T6  PC 495 PROFIBILIS DRV0 version Two wire interface up to 3	
FM Class I, Zn 1, AEx d IIC T6 FM Class II, Zn 21, AEx td T85 °C	•
• XP Class I, II, III Div 1 Groups C, D  RS 485 Modbus version Two-wire interface, up to 1 T6 Ta = 55 °C; Two-wire interface, up to 1	5 200 bit/
DIP Class II,III Div 1 Groups E, F, G T6 Ta = 55 °C; Class I, Zn 1, Ex d IIC T6 Ta = 55 °C; Class I, Zn 21, Ex tD T85 °C Ta = 55 °C  Connection cable to customer interface  Face  Connection cable to customer interface  Face  To permanently installed for A optional for standard	
Design, enclosure  Analog connection cable 10 x 2, with shielding in twi	
Degree of protection IP65 according to EN 60529 (only supplied cables may be used for ATEX configuration!) and number of I/Os used)	n type
Purging tube  • Length: 340 mm  • Outer diameter: 48 mm • Inside diameter: 44 mm  • Length: 340 mm  • PROFIBUS DP connection cable (with ATEX configuration: only supplied cables may be used!)  1 x 2 + 4 (PROFIBUS DP here) cable)	brid'
Purging tube  Length, outer diameter, inner diameter, inner diameter, inner diameter;  ter: 340, 48, 44 mm  Modbus connection cable (with ATEX configuration: only supplied cables may be used!)  1 x 2 + 3, with shielding in pair configuration	wisted-
Weights Cable length for ATEX configuration 3 m	
Detector unit     6.0 kg     Conductor cross-section  Min. 0.34 mm <sup>2</sup>	
• Transmitter unit 5.2 kg	
Frocess interface     Minimum handing and IV DDO 110 pmp.	
- for DN50/PN25 5.3 kg Millimum behaling radius ATEX-PRO- Figure 1.2 kg FIBUS	
Connection dimension customer flange  DN 50/PN 25, DN 50/PN 40 or ANSI 4"/150 lbs	

## In situ O2 gas analyzer

Sensor cable	Not included in standard delivery, permanently installed for ATEX or optional for standard
Sensor cable type configuration	4 x 2, with shielding, in twisted-pair configuration
Conductor cross-section	Min. 0.34 mm <sup>2</sup>
Cable sheath	PUR (polyurethane)
Dimensions	• Diameter: 11 mm • Length: up to 25 m
Minimum bending radius	ATEX: 85 mm
Climatic conditions	
Ambient temperature range	Note  The display on the receiver side must not be exposed to direct solar radiation.  • -20 +55 °C during operation (additional solar radiation not permissible!)  • -40 +70 °C during transport and storage
Temperature range on the sensor side of the process interface (connection plate)	-20 +70 °C
Atmospheric pressure	800 1100 hPa (for ATEX and FM version)
Humidity	< 100% rel. humidity
Measuring conditions	
Measurement path	$0.3\\ 8$ m (other lengths: please contact Siemens)
Process gas pressure, temperature	• O <sub>2</sub> : 900 1 100 hPa, 0 600 °C • O <sub>2</sub> : 700 5 000 hPa, 0 200 °C
Dust load	The influence of a high dust load is complex, and depends on the optical path length and particle size distribution.
Purging	
Purging gas • Quality • Dew point	Nitrogen (for O <sub>2</sub> applications) O <sub>2</sub> application: Purity better than 99.7% in order to achieve full performance. For oxygen measurements, an O <sub>2</sub> content < 0.01 vol.% in the purging gas is recommended. < -10 °C, condensation on the optics
	must be avoided
Sensor purging  Max. overpressure in the sensor  Purging gas temperature on sensor side	500 hPa 0 +55 °C
• Flow	$\rm O_2$ application: When commissioning a sensor enclosure previously filled with air: 3 5 l/min (for at least 15 min), subsequently: at least 0.25 l/min
Purging on the process side (optional)  • Pressure at purging gas inlet  • Flow	2 000 8 000 hPa Dependent on process gas pressure, process gas velocity, dust load, mois- ture, etc. up to max. 50 l/min

In situ O2 gas analyzer

### Accessories

#### SITRANS SL sensor alignment kit

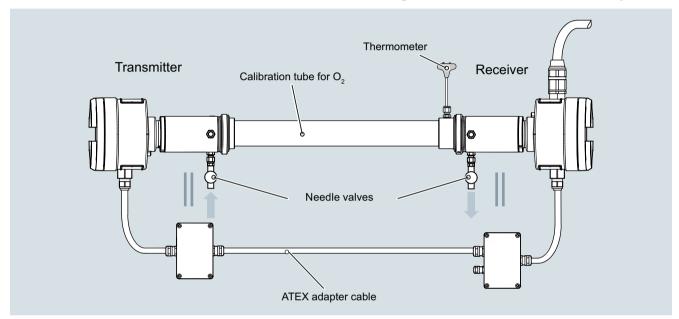
The SITRANS SL sensor alignment kit includes a battery-operated lamp, a centering aid with cross-hairs and two hook spanners for loosening the sensors from the flange connection plates.

#### Please note:

The SITRANS SL sensor alignment kit is not explosion-protected! Therefore it must never be used in a hazardous area without approval by the plant operator!

#### Calibration test kit

The SITRANS SL has already been factory-calibrated. If it is desirable or necessary to check the calibration, this can be performed using an external calibration test kit following removal of the transmitter and detector units. This procedure has no influence on the optical adjustment of the unit since the flange connection plates remain mounted on the customer flange. The calibration test kit for  $O_2$  consists of a stainless steel calibration tube and a thermometer. To carry out the calibration, it is mounted between the transmitter and receiver. The calibration tube for  $O_2$  can then be filled with air or a calibration gas.



Calibration validation setup of SITRANS SL O<sub>2</sub>

#### Additional accessories

You can find more accessories and spare parts in our PIA Life Cycle Portal product selector:

http://www.pia-portal.automation.siemens.com

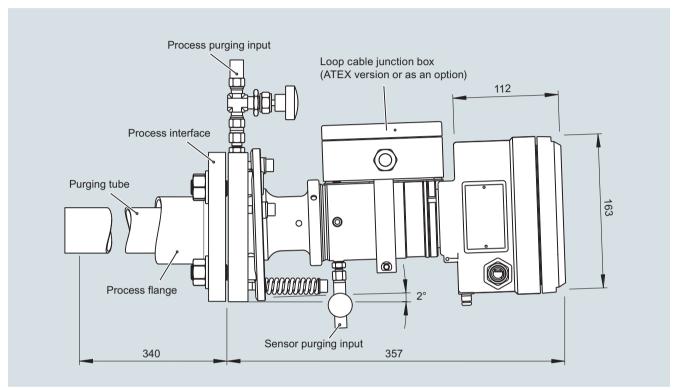
### In situ O2 gas analyzer

#### Dimensional drawings

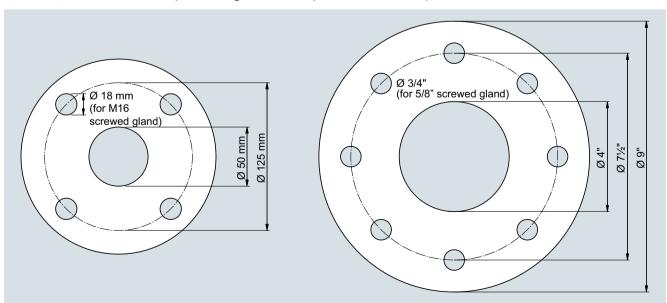
#### Note

The SITRANS SL sensors must be accessible from the side. A space of at least 60 cm must be provided next to the SITRANS SL transmitter and detector units in order to facilitate maintenance and servicing.

To fulfill the safety requirements, a clearance of at least 10 cm must be provided around the SITRANS SL to maintain cooling.



SITRANS SL, transmitter/detector unit (same housing for DN50/PN25 process interface version), dimensions in mm



Connection dimensions of process flanges provided by customer DN50/PN25 and ANSI 4"/150 lbs

In situ O2 gas analyzer

### Circuit diagrams

#### Electrical connections

Non-hazardous area version connection cable - customer interface

Terminal bl	lock in the receiver enclosure	Function/voltage	Ethernet cable
1	+	Power supply	
2	-	- 19 30.2 V, 10 VA <sup>1)</sup>	
3	Normally closed under power <sup>4)</sup>	Digital output 0 (relay)	
4		30 V, 0.5 A <sup>3)</sup>	
5	Normally closed under power <sup>4)</sup>	Digital output 1 (relay)	
6		30 V, 0.5 A <sup>3)</sup>	
7	+	Digital input 0	
8	-	- 0 30 V <sup>2)</sup>	
9	+	Analog output 0 (measurement)	
10	-	-30 V, 24 mÅ <sup>3)</sup>	
11	+	Analog output 1 (measurement)	
12	-	-30 V, 24 mÅ <sup>3)</sup>	
13	PROFIBUS A line (RxD/TxD_N Modbus D1 (RxD/TxD_N - data inverted)  PROFIBUS A line (RxD/TxD_N data inverted)	RS 485 (PROFIBUS/Modbus)	
14	PROFIBUS B line (RxD/TxD_P Modbus D0 (RxD/TxD_P - data - data not inverted) Modbus D0 (RxD/TxD_P - data not inverted)	-7 +12 V DC	
15	PROFIBUS/Modbus shield	-	
16	T <sub>X</sub> +	Ethernet <sup>5)</sup>	White/orange
17	T <sub>x</sub> -	<del>-</del> -	Orange
18	R <sub>x</sub> +		White/green
19	R <sub>x</sub> -		Green
20	+	Analog input 0 (temperature) - 0 30 mA <sup>2)</sup> , 120 Ω	
21	-	-0 30 mA <sup>2</sup> /, 120 <b>Ω</b>	
22	+	Analog input 1 (pressure) - 0 30 mA <sup>2)</sup> , 120 Ω	
23	-	-0 30 mA <sup>-7</sup> , 120 Ω	
24		Grounding	
25		Grounding	
Ground		Grounding	
Ground		Grounding	Shielding

<sup>1)</sup> This is the maximum power consumption of the SITRANS SL

<sup>2)</sup> These are the maximum input values

<sup>3)</sup> These are the maximum output values

Note:

"Normal operation" stands for normal operation of the analyzer. The system is connected to the voltage source and is running without problems; no error message generated or displayed.

"Normal under power" refers to the status of the relay under the above-named normal operation. The relay contact of the alarm signal is closed.

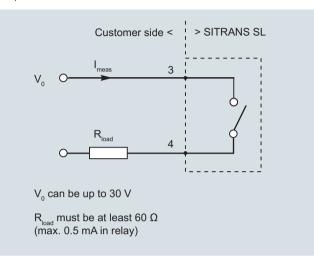
We recommend that the Ethernet connection is not made via the cable to the Ethernet terminals in the detector unit. Instead, the Ethernet connection should be made via the sensor cable connection set which is optionally available for the detector unit.

### In situ O2 gas analyzer

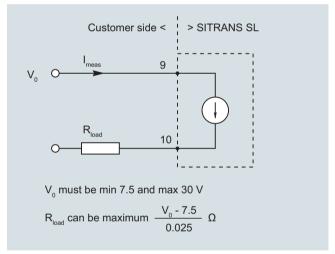
Examples of digital output and analog output

#### Caution

Please note that an external isolating power supply may be required!



Example of digital output 0



Example of an analog output 0

Sensor cable terminal box on the receiver side (ATEX version)

Terminal str	ip in terminal box	Function	Color code
1	+	24 V DC voltage supply	Red
2	-	for transmitter unit	Blue
3	Com +	Communication with trans-	Pink
4	Com -	- mitter	Gray
5	Sync +	Synchronization with trans-	White
6	Sync -	- mitter	Brown
7	NC	Not used	-
8	Tx+	Ethernet	Gray/pink
9	Tx-	_	Red/blue
10	Rx+		Black
11	Rx-	_	Violet
PE terminal	-	Grounding	Green
PE terminal		Grounding	Yellow
Gland		Grounding	Shielding

In situ O2 gas analyzer

		7MB6221-		Cannot be combined
	e online configuration in the PIA Life Cycle Portal.			
Explosion protection¹) Without Ex II 2 G Ex de op is IIC T6 Ex II 2 D Ex tD A21 IP65 T85°C FM USA: XP Class I, II, III Div 1 Groups A DIP Class II, III DIV 1 Group EFG Class I, Zn 1, AEx d IIC T6 Ta = : Zn 21, AEx tD T85°C Ta = 55°C FM Canada: XP Class I, III DIV 1 Group EFG Class I, Zn 1, Ex d IIC T6 Ta = : ST 21, AEx tD T85°C Ta = 55°C FM Canada: XP Class II, III DIV 1 Group EFG Class I, Zn 1, Ex d IIC T6 Ta = : Class II, III Zn 21, Ex t IIIC T85°C FM Canada: XP Class II, III DIV 1 Group EFG Class II, III Zn 21, Ex t IIIC T85°C FM Canada: XP Class II, III DIV 1 Group EFG Class II, III Zn 21, Ex t IIIC T85°C FM Canada: XP Class II, III DIV 1 Group EFG Class II, III Zn 21, Ex t IIIC T85°C FM Canada: XP Class II, III DIV 1 Group EFG Class II, III Zn 21, Ex t IIIC T85°C FM Canada: XP Class II, III DIV 1 Group EFG Class II, III DIV 1 Gro	e online configuration in the PIA Life Cycle Portal.  J. B. C. D T6 Ta = 55°C  Ta = 55°C  D T6 Ta = 55°C  Ta = 55°C  Ta = 55°C  Ta = 55°C  Length  340 mm  Purging: Sensor side  No purging  3 5 l/min  No purging  3 5 l/min  No purging  3 5 l/min  6L.), 150 lbs, MAWP (PS) at 20 °C: 232 psi 6L.), 125, MAWP (PS) at 20 °C: 2.5 MPa	Article No. 7MB6221-	O.  O.  O.  O.  O.  O.  O.  O.  O.  O.	Cannot be combined  Cannot be combined  A B B Cannot be combined
• 10 m • 25 m With stainless steel gland • 5 m • 10 m • 25 m			B C D E	B B C C C
Without cable			X	
Documentation language German English French Spanish Italian			0 1 2 3 4	

<sup>1)</sup> Complete and consistent implementation of the safety concept by the plant operator must be ensured during the commissioning and operation of the in-situ laser spectrometer SITRANS SL in hazardous atmospheres.

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<sup>&</sup>lt;sup>2)</sup> The examples shown represent possible applications where appropriately configured SITRANS SL solutions can be used. The user is responsible for the prevailing conditions (plant concept (possibly redundant), application of appropriate components required in addition, compliance with possible directives, etc.).

<sup>3)</sup> MAWP: Maximum Allowable Working Pressure.

### In situ O2 gas analyzer

Selection and ordering data		
Additional versions	Order code	
Add "-Z" to Article No. and specify Order code		
Acceptance test certificate 3.1 (leak test) in accordance with EN 10204	C12 <sup>1)</sup>	
Acceptance test certificate 3.1 (material certificate) in accordance with EN 10204	C13 <sup>1)</sup>	
SIL 1 conformity declaration in accordance with standards IEC 61508/IEC 61511 (for the measured component oxygen in combination with analog interfaces)	C20 <sup>1)</sup>	
TAG label, customized inscription	Y30	

 $<sup>^{\</sup>rm 1)}$  Together with explosion protection as per FM, on request

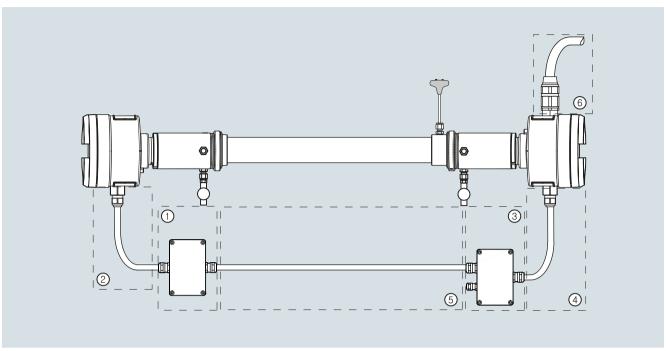
Selection and ordering data		
Additional units and spare parts	Article No.	Item no. (see graphic on page 2/21)
Additional units		
SITRANS SL, calibration test kit O <sub>2</sub> ,	A5E01000694	
SITRANS SL, sensor alignment kit	A5E01000740	
SITRANS SL, connection box Ex-e for 25-pin connecting cable	A5E01267567	
SITRANS SL, connecting cable set analog (for non-Ex)	A5E03328474	
SITRANS SL, connecting cable set PROFIBUS DP (for non-Ex)	A5E03328473	
SITRANS SL, UV protective hose for outdoor use, ND = 48 mm per 30 m length	A5E01714061	
SITRANS SL, sensor cable set (non-Ex) with cable glands of nickel-plated brass, length: 5 m	A5E02509347	3+4+5
SITRANS SL, sensor cable set (non-Ex) with cable glands of nickel-plated brass, length: 10 m	A5E02528048	3+4+5
SITRANS SL, sensor cable set (non-Ex) with cable glands of nickel-plated brass, length: 25 m	A5E02528052	3+4+5
Spare parts		
SITRANS SL, process connection plate (1 unit) for customer flange size: DN 50/PN 10 40 including seal	A5E01009881	
SITRANS SL, gasket for DN 50/PN 10 40	A5E02522036	
SITRANS SL, process connection plate (1 unit) for customer flange size: ANSI 4"/150 lbs including seal	A5E01009883	
SITRANS SL, gasket for ANSI 4"/150 lbs	A5E02789535	
SITRANS SL, purging tube 340 mm incl. seal for DN 50/PN 10 40	A5E01009892	
SITRANS SL, window cover for detector unit	A5E01009897	
SITRANS SL, cover for transmitter unit	A5E02568437	
SITRANS SL, connecting cable for analog and Modbus (ATEX), cable gland of nickel-plated brass, for devices delivered after October 2009 (Version 1.1)	A5E02608597	6
SITRANS SL, connecting cable for analog and Modbus (ATEX), cable gland of stainless steel	A5E34834297	6
SITRANS SL, connecting cable for PROFIBUS DP (ATEX), cable gland of nickel-plated brass	A5E02608594	6
SITRANS SL, cable for transmitter (ATEX), cable gland of nickel-plated brass	A5E44678580	2
SITRANS SL, cable for detector (ATEX), cable gland of nickel-plated brass	A5E44678567	4
SITRANS SL, connecting cable for PROFIBUS DP (ATEX), cable gland of stainless steel	A5E34834296	6
SITRANS SL, connecting cable for transmitter (ATEX), cable gland of stainless steel	A5E34830928	2
SITRANS SL, connecting cable for detector (ATEX), cable gland of stainless steel	A5E34831050	4
SITRANS SL, terminal box and connecting cable for transmitter (ATEX), cable gland of stainless steel	A5E34831075	1
SITRANS SL, terminal box (ATEX), cable gland brass, nickel-plated	A5E02091532	1
SITRANS SL, terminal box and connecting cable for transmitter (ATEX), cable gland of nickel-plated brass	A5E02568463	1+2
SITRANS SL, sensor cable 5 m	A5E02571180	5
SITRANS SL, sensor cable 10 m	A5E02571184	5
SITRANS SL, sensor cable 25 m	A5E02571186	5
SITRANS SL, terminal box and connecting cable for detector (ATEX), cable gland of stainless steel	A5E34831078	3
SITRANS SL, terminal box and connecting cable for detector (ATEX), cable gland of nickel-plated brass	A5E02568465	3+4
SITRANS SL, cable gland for non-ex cables	A5E02568457	
SITRANS SL, screw cap	A5E01010033	
SITRANS SL, printed-circuit board for detector with LUI (Version 1.1)	A5E31503119	
SITRANS SL, remote control IS, CSA, FM, ATEX certifications	A5E02091214	
SITRANS SL, assembly kit for needle valve	A5E02569944	
SITRANS SL, assembly kit restrictor for sensor purging	A5E02183375	

#### Additional accessories

You can find more accessories and spare parts in our PIA Life Cycle Portal product selector: http://www.pia-portal.automation.siemens.com

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In situ O2 gas analyzer



SITRANS SL spare parts, item numbers

### Documentation

### More information

The complete documentation is available in various languages for downloading free of charge: http://www.siemens.com/processanalytics/documentation